

Notice of References Cited	Application/Control No. 10/060,944	Applicant(s)/Patent Under Reexamination KIKUCHI ET AL.	
	Examiner Zia R. Hashmi	Art Unit 2881	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Matsui et al. "Wafer Inspection System and Wafer Inspection Process Using Charged Particle Beam", Pub. No: US 2002/0134936 A1, publication date: September 26, 2002.
	V	
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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